10/529340 JC17 Rec'd PCT/PTO 24 MAR 2005

In the Claims:

(Currently Amended) An integrated test circuit arrangement-(10) having integrated test structures (80 to 86), and having at least one of the following elements or units: at least one integrated heating element, (70) and/or an integrated detection unit-(102, 42), which detects at least one physical property in each case for each of the test structures (80 to 86),

and/or having an integrated supply unit, which supplies each of the test structures with a current or a voltage in each case in switchable fashion independently of one another, and

a control unit which is connected to outputs of the detection unit on an input side and which controls the supply unit dependent on the detection results.

2. (Cancelled)

3. (Currently Amended) The circuit arrangement (10) as claimed in claim 1-or 2, characterized in that wherein the test structures (80 to 86) of a first group (T1) have the same construction among one another.

and/or in that the test structures (80 to 86) of a group are or contain interconnects which preferably contain a metal or comprise a metal and/or which are led into another metallization layer by means of a via or contact hole.

and/or in that the test structures of a group (T2) are or contain dielectrics.

and/or in that the test structures of a group (T3) are or contain active or passive electronic components, in particular transistors, capacitors, resistors or coils,

and/or in that the test structures of different groups are integrated in the circuit arrangement (10), preferably spatially, in particularly in different planes parallel to the plane of a carrier substrate for the test structures (T1 to T5),

and/or in that a group (T1 to T5) contains more than fifty or more than one hundred or more than one thousand test structures.

4. (Currently Amended) The circuit arrangement-(10) as claimed in ene of the preceding claims, characterized by a claim 1, wherein at least one of:

supply unit (40, 40a), which feeds the test structures (80 to 86) with a current or a voltage in each case in switchable fashion preferably independently of one another,

and/or the supply unit containing contains at least one of: a multiplicity of integrated current sources (60 to 68) and/or a multiplicity of integrated voltage sources, and

and/or the current sources (60 to 68) containing contain a plurality of current mirrors which in each case generate a multiple or a fraction of a reference current or a current having the magnitude of the reference current.

5. (Currently Amended) The circuit arrangement-(10) as claimed in one of the preceding claims, characterized in that claim 2, wherein the heating element-(70) at least one of:

contains a resistance heating element which preferably contains monocrystalline silicon or polycrystalline silicon or comprises monocrystalline silicon or polycrystalline silicon or which contains a metal or comprises a metal, the silicon preferably being doped, and

and/or in that the heating element (70) has a straight profile, a meandering profile, a triangular function profile or a rectangular function profile.

6. (Currently Amended) The circuit arrangement—(10) as claimed in one of the preceding claims, characterized by claim 1, further comprising at least one reference structure—(88), at least one of the construction and/or the dimensions of which differ from the construction and/or the dimensions of a the test structure—(80 to 86).

7. (Currently Amended) The circuit arrangement (10) as claimed in ene of the preceding claims, characterized in that claim 1, wherein the detection unit at least one of:

is connected or can be connected to the test structures (80 to 86), and

and/or in that the detection unit-contains at least one counter unit-(36), which is clocked in accordance with a predetermined clock-(T).

8. (Currently Amended) The circuit arrangement-(10) as claimed in one of the preceding claims, characterized in that claim 1, wherein at least one of:

the detection unit contains at least one multiplexer unit-(102), the inputs of which are electrically connected to a respective test structure-(80 to 86), and

and/or in that the <u>an</u> output of the multiplexer unit (102) is connected to the <u>a first</u> input of a comparison unit (42a), the other <u>a second</u> input of which is electrically connected to a reference structure (88), the reference structure (88) having <u>at least one of</u> a different construction and/or different dimensions than a-the test structures (80 to 86).

9. (Currently Amended) The circuit arrangement—(10) as claimed in ene of the preceding claims, characterized by a claim 1, wherein the control unit—(34), which is connected to the outputs of the detection unit on the input side and which outputs at least one of: detection results, and/or which controls the supply unit in a manner dependent on the detection results and/or which outputs a datum for ascertaining the detection instant and/or which outputs a datum for identifying a-the_test structures.

10. (Cancelled)

11. (Currently Amended) The circuit arrangement (10) as claimed in one of the preceding claims, characterized in that the circuit arrangement (10) contains claim 1, further comprising electronic components associated with a user circuit, in particular with a memory unit and/or with a processor.

- 12. (Currently Amended) The circuit arrangement (10) as claimed in ene of the preceding claims, characterized in that claim 1, wherein the circuit arrangement (10) is encapsulated in a plastic housing or in a ceramic housing.
- 13. (Currently Amended) A method for testing test structures, (80 to 86), in particular with a circuit arrangement (10) as claimed in one of the preceding claims, having the method comprising the following steps that are implemented without limitation by the order specified:

integration of integrating test structures (80 to 86) into an integrated circuit arrangement (10),

integration of integrating a detection unit-(102, 42) into the integrated circuit arrangement, which detects the detection unit detecting at least one physical property for of the test structures,

integration of integrating at least a part of a supply unit (60 to 68) into the integrated circuit arrangement (10),

connection of connecting the test structures (80 to 86) to the supply unit (60 to 68) or to a supply unit,

detection in each case of a<u>detecting one of the</u> physical property properties of <u>each of</u> the test structures (80 to 86) by means of the detection unit (102, 42) or by means of a detection unit, and

integrating a control unit into the integrated circuit arrangement, which is connected to outputs of the detection unit on an input side and which controls the supply unit dependent on the detection results.

14. (Currently Amended) The method as claimed in claim 13, characterized by further comprising at least one of the following steps:

integration of integrating at least one heating element (70) into the integrated circuit arrangement (10),

warming or heating ef-the test structures (80 to 86) with the aid of the heating element (70), and

and/orconnecting the supply unit-(60 to 68) being connected to the test structure during warming or during heating.

15-16. (Cancelled)

17. (Currently Amended) The method as claimed in one of claims 13 to 16, characterized by claim 13 further comprising the following steps:

integration of integrating at least one reference structure (88), at least one of the construction and/or the dimensions of which differ from the construction and/or the dimensions of a-the test structures (80 to 86),

detection of a detecting one of the physical reference property properties at the reference structure (88),

comparison of comparing the one of the physical properties property of a test structure (80 to 86) with the a reference property or comparison of comparing a quantity generated from a the one of the physical property properties and a quantity generated from the reference property, and/or registering of an instant at which the comparison result changes.

- 18. (Currently Amended) The method as claimed in one of claims claim 13 to 17, characterized in that preferably wherein the same the physical properties of different test structures (80 to 86) are successively compared with a reference property.
- 19. (Currently Amended) The method as claimed in one of claims 13 to 18, characterized in that claim 14, wherein the heating element (70) is at least one of:

fed with at least one of an AC current and/er a DC current, and/er in that the heating element (70)

is-heated to temperatures of greater than two hundred degrees Celsius or greater than three hundred degrees Celsius.

- 20. (Currently Amended) The method as claimed in ene of claims 13 to 19, characterized in that claim 13, wherein an output circuit (34) is integrated into the integrated circuit arrangement (10), which the output circuit outputs at least one set of detection data for the test structures (80 to 86).
- 21. (Currently Amended) The method as claimed in <u>claim 13</u>, <u>wherein the method one of claims 13 to 20</u>, <u>characterized in that it is implemented at least one of:</u>

with an unencapsulated integrated circuit arrangement-(10), in particular with an integrated circuit arrangement (10) that has not yet been incorporated into a housing, and/or

with an integrated circuit arrangement-(10) that is still arranged on a semiconductor wafer, the semiconductor wafer preferably carrying a multiplicity of other integrated circuit arrangements, and/or in that the method is implemented

for the purpose of monitoring ongoing production.

- 22. (Currently Amended) The method as claimed in one of claims 13 to 21, characterized by the following step: integration of claim 13, further comprising integrating at least a part of the supply unit-(60 to 68) into the integrated circuit arrangement-(10), said part containing at least one active component, preferably a transistor.
- 23. (New) The circuit arrangement as claimed in claim 2, wherein: the test structures of a second group contain interconnects which at least one of: comprise a metal or are led into another metallization layer by means of a via,

the test structures of a third group contain dielectrics, or the test structures of a fourth group contain active or passive electronic components.

- 24. (New) The circuit arrangement as claimed in claim 11, wherein the electronic components comprise at least one of a memory unit and a processor.
- 25. (New) The method as claimed in claim 17, further comprising registering an instant at which the comparison result changes.